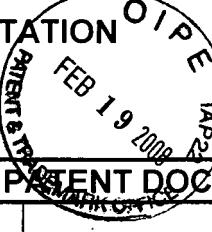


FORM PTO-1449 (Modified) US Patent and Trademark Office		US DEPARTMENT OF COMMERCE		Docket No. 050623.245	Application No. 10/623,908		
INFORMATION DISCLOSURE CITATION in an Application (Use several sheets if necessary)				Applicant Paul John Kawula			
				Filing Date July 21, 2003	Group Art Unit 3738		
U.S. PATENT DOCUMENTS							
Examiner Initial	Ref. No.	Document Number	Date of Patent	Name	Class	Subclass	Filing Date if Appropriate
	A1						
U.S. PATENT APPLICATIONS							
Examiner Initial	Ref. No.	Document Number	Date of Patent	Name	Class	Subclass	Filing Date if Appropriate
	A2						
FOREIGN PATENT DOCUMENTS							
Examiner Initial	Ref. No.	Document Number	Date of Publication	Country	Class	Subclass	Translation
	B1	WO 2005/113856	12/1/05	WIPO			Yes No
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
C1	Aluminium oxide, Wikipedia, the free encyclopedia, downloaded from http://en.wikipedia.org/wiki/Alumina , June 12, 2007, 5 pgs.						
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C4	Chen, "New Coating Process Enables Higher-Efficiency Engines", Berkeley Lab Research News, 1996, 3 pgs.						
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EXAMINER				DATE CONSIDERED			
EXAMINER: Initial if references considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							